Steady-state and time-dependent LPP modelling





J. White University College Dublin



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<u>Outline</u>

1. A steady state plasma (optically thin)

4d-4f + 4p-4d emission: statistical UTA (*gf*), ion distribution $f_z = f(T_e)$ n_e and pulse length (YAG and CO₂)

2. A time-dependent 1-D plasma (optically thick)

ion distribution, $f_z = f(r,t)$, hydrodynamics [Medusa], some diagnostics N_i , N_j level populations for radiation transport [UCD], 2 surveys: power density and pulse length (optimum laser conditions)

3. A 2-D plasma

time-dependent spectra [EPPRA, Z*] spatial pulse shape (flat-top/Gaussian) pulse length results

Conclusions

0. Introduction

- quantify 2% in-band emission (13.365-13.635 nm)
- source metric: *F* (steady-state), CE (time-integrated)

1) "optically thin" – doped tin (5% tin by number)



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<u>1. 'Steady-state'</u> (oscillators weighted by ion distribution) $gf \bullet f_z$



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1. Experimental comparison

long wavelength match at lower temperatures 30-35 eV

5% tin by number (optically thin) Jenoptik 0.25-m grazing incidence flat field spectograph (UCD)



1. Experimental comparison

short wavelength match at higher temperatures 43-50 eV

5% tin by number (optically thin) Jenoptik 0.25-m grazing incidence flat field spectograph (UCD)



1. Statistical representation '4d' subshell ions: Sn VII-Sn XIV

- $\mathbf{H} \psi = \mathbf{E} \psi$
- statistical "three-parameter" Gaussian (mean, standard deviation, Σgf) versus λ



1. Rate equations: ionisation vs recombination

- ion distribution f_z from rate equations (from atomic processes)
 - collisional ionisation, S(z-1)
 - radiative recombination, $\alpha_r(z)$
 - three-body recombination, $\alpha_{3b}(z)$
 - semi-empirical
- a balance of ionisation and recombination



$$\begin{split} \mathbf{S} &= \mathbf{9} \; \mathbf{x} \; \mathbf{10^{-6}} \; \boldsymbol{\xi_z} \; (\mathbf{T_e} / \; \boldsymbol{\chi_z})^{1/2} \; \mathbf{e} \; {}^{(-\boldsymbol{\chi_z} / \; \mathbf{T_e})} \\ & \boldsymbol{\chi_z}^{3/2} \; (\mathbf{4.88} + \mathbf{T_e} / \; \boldsymbol{\chi_z}) \end{split}$$

$$\begin{aligned} \alpha_{\rm r} &= 5.2 \ \text{x} \ 10^{\text{-14}} \ (\chi_{\rm z} \, / \, \text{T}_{\rm e})^{1/2} \ \text{Z} \\ & [0.429 + .5 \ \log(\chi_{\rm z} \, / \, \text{T}_{\rm e}) + 0.469 \ (\text{T}_{\rm e} \, / \, \chi_{\rm z})^{1/2}] \end{aligned}$$

$$\alpha_{3b} = 2.97 \times 10^{-27} \xi_z$$
$$T_e \chi_z^2 (4.88 + T_e / \chi_z)$$

- **S** = collisional ionisation,
- α_r = radiative recombination,
- D_i = dielectronic recombination,
- α_{3b}^{-} = three-body recombination,
- T_e = electron temperature,
- n_e = electron density,
- Z = atomic number,
- χ_z = ionisation potential,
- ξ_z = number of open shell electrons,
- z = ion stage.

1. Nd:YAG and CO2

Optimising 13.5-nm emission as a function of laser wavelength

- $n_e (CO_2) = 1/100 n_e (YAG)$
- lower power density to achieve 40 eV ($\lambda^2 \phi$ = constant)



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2. What is the emission as a function of time/space?

timedependent plasma d*n*/dt ≠ 0





time-dependent: sharp temperature gradients

 $t(\text{atomic processes}) \sim t(\text{laser})$ $n_e \text{ and } T_e = f(r, t)$

c.f. steady-state: one temperature t(atomic processes) < t(laser) $n_e = n_{ec} \approx 10^{21} \lambda^{-2} \text{ and } T_e \propto \mathbb{Z}^{1/5} (\lambda^2 \phi)^{3/5}$

- FORTRAN laser-plasma interaction code Medusa
- one-dimensional Lagrangian difference mesh
- hydrodynamics variables: **density** (ρ), **velocity** (v), **ion temperature** (T_i), **electron temperature** (T_e) as functions of **space** (r) and **time** (t) from Navier-Stokes equations
- **average atom model** (to simplify rate equations especially for high Z). $P_n = n$ shell occupation number.
 - excitation/de-excitation included (*I*-degenerate level populations calculated from average atom model)

2. Sn hydrodynamics: vs (r,t)

simulation: 400 cells, 100 ns, cylindrical geometry versus cell at: 18, 23, 28 ns (POP: 23 ns) 15-ns FWHM $7 - 10^{6}$ 10² velocity electron density electron temperature 28 ns 6 10²³ 50 23 ns 5 Electron temperature (eV) 10²² Electron density (cm⁻³) 4 18 ns Velocity (cm/sec) 10²¹ 3 2 10²⁰ 28 ns 23 ns 18 ns 10¹⁹ 10 Ω 18 ns 28 ns 23 ns 10¹⁸ 0 100 200 300 400 500 600 700 800 900 1000 0 100 200 300 400 500 600 700 800 900 1000 100 200 300 400 500 600 700 800 900 1000 0 Distance (µm) Distance (µm) Distance (µm) x 10[℃] 10²⁴ 9 60 6.6e+003 un 8 10²³ 50 7 10²² 6 Electron temperature (eV) R 8 8 9 0 Electron density (cm⁻³) 10² 5 Velocity (cm/sec) 3.7e+003 µr 10²⁰ 4 30 10^{19 |} 3 2 10¹⁸ 5.8e+002 µm 3.7e+003 μn 5.8e+002 µn 10 10¹⁷ Ω 6.6e+003 μn 6.60+003 Lin 5.80+002 Lin 10¹⁶ -1 0 L 0 20 60 80 100 120 0 40 20 40 60 80 100 0 120 20 40 60 80 100 120 Time (ns) Time (ns) Time (ns)

versus time at: 400, 392, 384

laser: $P_{equiv} = 1.3 \times 10^{11} \text{ W/cm}^2$

target: solid tin, 50 µm-diameter wire

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<u>2. Ion distribution = f(r,t)</u> 1-D x time Peak of the pulse

• Sn⁴⁺ -- Sn¹³⁺ ion fraction and ion density (cm⁻³)



2. Time-dependent plasma: Sn level populations (for $\Delta n = 0$)

• Sn V – Sn XIV UTA (/ degeneracy removed with energy functional)



Population number densities (N_i , N_j) cm³ versus distance (μ m)

*E*₀: black: 4p⁶4d^N green: 4p⁶4d^{N-1}4f¹ blue: 4p⁵4d^{N+1} red: 4p⁶4d^{N-1}5p¹

J. Appl. Phys. 101 043301, 2007

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2. All together: sum up intensity with absorption

laser

radiation

(to spectrometer)

 $I_m = f(r,t) \rightarrow I = f(\lambda,t)$

- cell width, Δz (Medusa)
- absorption cross section, χ



The emission as a function of time, *I*_{out}, is calculated by summing up attenuated cell emission over all *m* cells

nl level populations as a function of r,t

for $4p^6 4d^N$, $4p^{64}d^{N-1}4f^1$, $4p^{54}d^N$, and $4p^{64}d^{N-1}5p^1$ configurations

The rest is atomic accounting (*a.k.a.* computational physics)

10 ions 3 transitions 6 shells (SHM) 400 x 400 cells (summed attenuated absorption) or 200 x 401 = 80200 cells 100 timesteps 200 frequency points in 2% bandwidth

~ 3 x 10¹¹ (300 billion) calculations/spectrum

But the good news: only 3 UTA transitions instead of 100,000 in the line-by-line analysis

So 300 billion calculations/spectrum instead of 10 thousand trillion!

2. Sn time-integrated UTA spectra

laser: 1.064 µm, 15.0 ns (FWHM), Gaussian target: solid tin, 90 µm-diameter wire simulation: 400 cells, 100 ns, cylindrical geometry





Calculated spectra: intensity versus wavelength

2. Sn UTA spectra versus time

laser: 1.064 µm, 15.0 ns (FWHM), Gaussian target: solid tin, 90 µm-diameter wire simulation: 400 cells, 100 ns, cylindrical geometry

• power density from 0.5 to $3.0 \times 10^{11} \text{ W/cm}^2$



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2. Sn time-integrated UTA spectra

laser: 1.064 µm, 15.0 ns (FWHM), Gaussian target: solid tin, 90 µm-diameter wire simulation: 400 cells, 100 ns, cylindrical geometry

- power density from 0.5 to 3.0 x 10¹¹ W/cm²: max CE at 0.8 x 10¹¹ W/cm²
- pulse width from 7 to 23 ns: max CE for 10-ns FWHM (4% > than at 15-ns)



Calculated spectra: intensity versus wavelength

2. Experimental comparison

- Calculated: 0.8 x 10¹¹ W/cm²
- Experimental: 0.9 x 10¹¹ W/cm²



Experimental and calculated spectra

J. Appl. Phys. 99 093302, 2006

2. Conversion efficiency

- power density survey: max CE at 0.8 x 10¹¹ W/cm²
- Lateral expansion not included!



Conversion efficiency (%) versus power density

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Frame 001 | 01 Feb 2007 | ZSTAR - code output, cell values | ZSTAR - code output, cell values | ZSTAR - code output,

3. 2D plasma

Z* EPPRA

Implicit, E-L MHD, average atom code, solves ionisation kinetics selfconsistently with radiation transfer

82 x 69 grid, YAG



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3. 2D plasma: pulse shape (spatial)

- Z* (EPPRA): 2D LPP simulation
- 2.2-ns Gaussian at peak emission

Electron temperature



in-band emission (into 4π)



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3. 2D plasma: pulse shape (spatial and temporal) Appl. Phys. Lett., 92, 151501, 2008

- calculated Gaussian, flat-top, and experiment (Osaka ILE) 2.2 ns
- CE versus laser power density .66 µm, ..27 µm diameter



3. 2D plasma: pulse shape (spatial and temporal) Appl. Phys. Lett., 92, 151501, 2008

- CE versus laser power density .48 µm, .27 µm diameter



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3. 2D plasma (emission lags max pulse)

- Input (laser) and output (spectral response)
- Pulse and emission curves plotted together

Normalized to one in-band emission and laser power versus time.

In-band emission (into 4π) versus laser power for different beam profiles (flat-top in blue and Gaussian in black).

Conclusions

- steady-state (optically thin) plasma:
 - statistical model: source brightness $F \rightarrow 40 \text{ eV}$
- time-dependent plasma (optically thick):
 - energy functional for UTAs \rightarrow more manageable computation!
 - radiation transport but no lateral expansion
 - max CE \rightarrow 0.8x10¹¹ W/cm² and 10 ns.
- What's next?
 - CO₂ modelling, pulse shaping, and pre-pulse-pulse

Some recent references

"Tin laser-produced plasma source modelling at 13.5 nm for extreme ultraviolet lithography," J. White, G. O'Sullivan, S. Zakharov, P. Choi, V. Zakharov, H. Nishimura, S. Fujioka, and K. Nishihara, *Appl. Phys. Lett.*, 92, 151501, 2008

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UCD Modelling Collaborations

John Costello, Paddy Hayden, Pat Yeates

突破EUV光源的瓶颈

Chenzong Dong, Mao Gen Su

David Ruzic

H. Nishimura, S. Fujioka, K. Nishihara

Sergey Zakharov, Vasily Zakharov, Peter Choi

Accelerating the next technology revolution.

Gerry O'Sullivan Rebekah D'Arcy Padraig Dunne Kenneth Fahy Colm Harte Oran Morris Tom McCormack Aodh O'Connor Fergal O'Reilly Paul Sheridan Emma Sokell Eileen Weadick John White Spectroscopy of atoms and ions in laser-produced plasmas. Atomic structure calculations.

Laser produced plasmas for EUV light source lithography. Spatial and temporal analysis of laser plasmas. Statistics of complex level structure and spectra. Synchrotron-based photoelectron spectroscopy. Photoabsorption of ions.

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- Baron Baltimore (a.k.a. Lord Baltimore)
- Baile an Tí Mhóir and Dún na Séad

